

AMENDMENTS TO THE SPECIFICATION:

Please replace the paragraph beginning on page 6, line 4, with the following amended paragraph:

As described above, if the mirror 30 inclines over the substrate 10 maintaining a predetermined angle, in general 45 degrees, due to an external magnetic field, light incident on the micromirror actuator parallel to the surface of the substrate 10 will be reflected in a direction perpendicular to the surface of the substrate 10. When an external magnetic field is no longer applied, the torsion bar 31 acts to return the mirror 30 inclined over the substrate 10 to its original state of being parallel to the surface of the substrate 10. If the external magnetic field is applied in a direction perpendicular to the substrate 10, as described above, the magnets 40 formed on the mirror 30 tends to follow the direction of the external magnetic field, and thus the mirror begins to rotate about the torsion bar 31 while overcoming the elastic forces of the torsion bar 31. The rotation angle of the mirror 30 is the angle at which magnetic torque applied by the external magnetic field and the opposing elastic forces of the torsion bar 31 reach an equilibrium state. As the strength of the external magnetic field increases, the rotation angle of the mirror 30 increases to the extent that the lower bottom surface of the mirror 30 contacts the inclined contact surface 51 of the groove 50. Thus, the maximum rotation angle of the mirror 30 is determined by the inclination contact surface 51. Therefore, even if the strength of the external magnetic field continuously increases, it is possible to maintain the inclined angle of the mirror 30 and prevent the torsion bar 31 from being abnormally deformed.